


Application No. 09/921,786  
Attorney's Docket No. 000348-280  
Page 2

**IN THE ABSTRACT:**

Kindly revise the Abstract which follows on a separate sheet:

**ABSTRACT**

 Method for real-time control of the fabrication of a thin-film structure comprising a substrate by ellipsometric measurement in which:

- variables directly linked to the ellipsometric ratio  $\rho = \tan\Psi \exp(i\Delta)$  are measured; and
- the said variables are compared with reference values. The comparison relates to the length of the path traveled at a time  $t$  in the plane of the variables with respect to an initial point at time  $t_0$ , for each layer participating in the thin-film structure.

Figure 2